

## Index

### **a**

absorbing polarizer 13, 14  
 acoustic wave device 338, 339  
 acousto-optic beam deflector (AOBD) 68–73  
     applications 73  
     cylinder lensing effect 72  
     modulation transfer function 71–72  
     optical deflector resolution 70–71  
     scan fly back time 72  
     schematic setup of 70  
 acousto-optic frequency shifter 73–76  
     double pass 75  
     laser Doppler vibrometer 75–76  
     low frequency shifts 75  
     operation principles 73–75  
 acousto-optic materials 51, 53, 54, 64, 68, 124–134  
     leadmolybdate 125  
     lithium niobate 131–134  
     requirements 125  
     tellurium dioxide 125–131  
 acousto-optic modulator (AOM) 59–69, 75, 78, 79, 118, 121, 129–131  
     analog modulation 66–67  
     applications of 68–69  
     construction 64–65  
     defined 63–64  
     digital modulation 65–66  
     dynamic contrast ratio 67  
     non-resonant 64  
     two-channel 68, 69

acousto-optic super-lattice modulation (AOSLM) 80, 81  
 acousto-optic tunable filters (AOTFs) 63, 83–124, 126, 127, 132, 133  
     advantages 88  
     autonomous tunable filter system 101–106  
     description 83  
     detectors for HPLC 106–109  
     infrared multispectral imaging 86–88  
     IR spectrometers 112–121  
     calibration target 120–121  
     electronics box (EB) 119–120  
     environmental requirements and characterization 121  
     instrument concept 115–116  
     optical box 116–120  
     multidimensional fluorimeter 90–93  
     multiwavelength thermal lens spectrometer 94  
     near infra-red (NIR)  
         spectrophotometer 95–98  
     NIR detector for FIA 109–112  
     NIR spectropolarimeter 98–101  
     non-collinear design 84  
     operation principles 83–86  
     satellite and space-based applications 112–124  
 acousto-optical Q-switch 76–83  
     applications 77–83  
     schematic representation of 77

- acousto-optics 59–134, 434, 437  
 acousto-optic effect, principle of 61–62  
 defined 59  
 history of 59–61  
 activation loss (AL) 335  
 all-fiber sensors 207–209  
 anisotropic medium 1, 7, 84, 277  
 anti-ferromagnetic materials 149, 150, 160  
 antiferromagnetic compounds 159–161  
 antiferromagnetic spintronics 160  
 anti-ferromagnets 149, 150, 159–161, 235  
 appropriate insulation (MV) 323  
 artificial path difference 270  
 atomic theory, of photoelasticity 33–35  
 autocorrelation technique 453  
 autonomoustunable filter system, AOTF-based 101–106  
 auxiliary controller 119
- b**
- barium strontium titanate  $\text{Ba}_{1-x}\text{Sr}_x\text{TiO}_3$  (BST) 266, 268, 327–328  
 barium titanate ( $\text{BaTiO}_3$ ) 288, 359  
 crystals 266  
 high transmittance 288–289  
 light phase modulator 266  
 plasmonic interferometer 292–293  
 waveguide electro-optic modulator 289–292  
 biaxial crystals 2, 3  
 wave surface for 5, 6  
 bi-material notches 50  
 binary phase shift keying (BPSK) 304  
 birefringence 1, 6–8, 14, 15, 17, 27–29, 35, 36, 45, 51, 121, 132, 143, 147, 153–155, 158, 159, 161, 170, 191, 208, 209, 211, 218, 265, 268, 274, 275, 328, 329, 423, 446, 462, 463  
 birefringent 6, 7, 15, 19, 27, 28, 45, 83, 86, 99, 127, 145, 265, 274, 329  
 birefringent  $\text{LiNbO}_3$  electro-optic waveguide (BEOW) 320  
 birefringent materials 6, 15  
 birefringent wave plate 14–16, 19  
 bismuth ferrite 359  
 bismuth silicon oxide,  $\text{Bi}_{12}\text{SiO}_{20}$  (BSO) 287, 449  
 Bragg cells 63, 73, 75, 76  
 Bragg diffraction 59, 61–63, 116  
 Brewster, D. Sir 27–29  
 Brewster constant 28  
 Brewster's angle 17  
 broadband optical isolator 22  
 buffer layer deposition 301  
 bulk optic sensors 207, 209–211
- c**
- carbonates 112, 114  
 cavity dumper 68  
 centre aperture detection (CAD) 240  
 cerium-doped  $\text{BaTiO}_3$  photorefractive crystal, fast switching of 440–444  
 chemical solution deposition (CSD) 340  
 circular magnetic birefringence (CMB) 147  
 circular magnetic dichroism (CMD) 149  
 circular polarization 12, 15, 22, 145  
 CMOS-compatibility 367–368  
 coherence gated holographic imaging 455–457  
 coherent receiver 268, 304–305  
 common path interferometer (CPI) 315  
 compact disk rewritable (CD-RW) 219  
 complementary metal–oxide–semiconductor (CMOS) 157, 310, 355, 367, 368  
 compatibility 367–368  
 computer generated holograms (CGHs) 453  
 coplanar-waveguide (CPW) 304  
 Cotton–Mouton effect 144, 147, 148  
 coupler interferometer (CI) 314–315  
 critical angle, of material 7  
 crystal optics, defined 1  
 crystal symmetry, effect of 3–4

**d**

DEMON 424  
 dense wavelength division multiplexing (DWDM) 329, 332, 334, 432, 470–472, 474  
 Detector's preamplifier 116  
 dichroism 20, 153–155, 170, 171, 218  
 differential group delay (DGD) 334  
 digital direct synthesizers (DDS) 103, 104  
 diode array detectors (DADs) 106, 108, 109  
 direct fringe writing process 453  
 directional couplers 132, 200, 201, 282–285, 363, 467  
 domain wall displacement detection (DWDD) 241, 242  
 Doppler shift 73, 75, 76  
 double refraction 1, 3, 6, 7, 20, 28, 30, 281, 282  
 dynamic contrast ratio (DCR) 67  
 dynamic gain flattening filters (DGFF) 335–338  
 dynamic photoelasticity 29, 50  
 dynamic polarization controller 334, 335  
 dynamic wave retarder 277–278

**e**

Eclipse<sup>TM</sup> VOA device 333  
 elasto-optic coefficients (EOCs) 32, 52, 61  
 elasto-optic effect 83, 275  
 electrically switchable cylindrical Fresnel lens 460–467  
 electric field sensors 268, 310, 316, 320  
 electro-optic (EO) 269–371  
 lens 295  
 tuning 307, 323, 324, 327  
 electron beam lithography 199, 306  
 electronics box (EB) 112, 115, 116, 119, 120  
 electro-optical plasmonic modulators 270  
 electro-optic deflector (EOD) 340, 347–350

electro-optic devices 266, 268, 275–288  
 directional couplers 282–285  
 dynamic wave retarder 277–278  
 intensity modulators (type 1) 278–279  
 intensity modulators (type 2) 279–280  
 phase modulator 275–276  
 PROM 287–288  
 scanners 280–282  
 spatial light modulators (electrically addressed) 285  
 spatial light modulators (optically addressed) 285–287  
 electro-optic directional coupler 283, 284  
 electro-optic effects 265–275, 283, 285, 287, 289, 293, 299, 311, 316, 328, 329, 335, 347, 348, 411, 415, 419, 422, 427, 429, 434, 445  
 electro-optic devices  
 directional couplers 282–285  
 dynamic wave retarder 277–278  
 intensity modulators (type 1) 278–279  
 intensity modulators (type 2) 279–280  
 phase modulator 275–276  
 PROM 287–288  
 scanners 280–282  
 spatial light modulators (electrically addressed) 285  
 spatial light modulators (optically addressed) 285–287  
 history 265–270  
 phenomenological theory  
 linear electro-optic effect 272–274  
 quadratic electro-optic effect 274–275  
 principles 270–271  
 electro-optic materials and applications 288–354  
 BaTiO<sub>3</sub> 288–293  
 LiTaO<sub>3</sub> 295–298  
 SHG 295–298

- electro-optic materials and applications (*contd.*)
- PLZT 293–295
  - electro-optic tunable etalon 294
  - electro-optic medium, refractive index of 270
  - electro-optic modulators 38, 266, 268, 269, 276, 285, 286, 288, 291, 292, 310, 311, 328, 338, 340
  - electro-optic phase retardation device 266, 293
  - electro-optic plasmonic materials and applications 354–371
  - CMOS-compatibility 367–369
  - silicon waveguide-based modulators 364–368
  - transparent conducting oxides 360–363
  - ultra-compact plasmonic modulators 362–364
  - electro-optic prism 281
  - electro-optic Q-switching 37, 330–332
  - electro-optic scanner 295
  - electro-optic tunable filter 329–330
  - elliptical polarization 12–13
  - E-O modulators 301, 340
  - epsilon-near-zero (ENZ) 356, 357, 366, 367
  - equatorial Kerr effect 149
  - Equinox<sup>TM</sup> 336, 337
  - erbium-doped fiber (EDF) 80
  - erbium doped fiber amplifier (EDFA)
    - based NIR spectrophotometer 95–98  - erbium-doped fiber amplifiers (EDFAs) 89, 96, 332
  - EuSe magneto-optic modulator 169
  - ExoMars rover 112, 113, 121
  - extinction ratio (ER) 132, 154, 280, 307–309, 316, 358, 459
  - extraordinary ray 5, 7, 8, 84, 125
  - extraordinary wave surface 4
- f**
- fabricated electrical contacts 307
  - fabricated optical devices 307
  - false-color scanning electron microscope (SEM) 307
  - Faraday effect 143–147, 149, 152, 161, 166–168, 170, 186, 191, 192, 206, 218
  - Faraday rotation 36, 146, 147, 150, 151, 154, 155, 158–161, 163–167, 169, 174, 177, 191, 192, 197, 198, 227
  - fast inter-band photorefractive effect 434
  - fast varifocal lenses 346–347
  - femtosecond pulses 268, 299
  - ferrimagnetic compounds 156–159
  - ferrimagnetic garnet oxide crystals 191
  - ferrimagnetic materials 149–151
  - ferrimagnetic RE-TM films 228, 229
  - ferrites 150, 152, 164, 179–183, 185, 189, 214
  - ferroelectric crystals 54, 55, 274, 295, 426
  - ferroelectric memory (FRAM) 119
  - ferrofluids 153, 155, 156, 175, 176
  - ferromagnetic HgCdCr<sub>2</sub>Se<sub>4</sub>
    - semiconductor, magneto-optical response of 153  - ferromagnetic materials 149–151, 160, 211
  - ferromagnetic semiconductors 152–153
  - fiber Bragg grating (FBG), acousto-optic interaction 78–82
    - long-wavelength regime 79
    - short-wavelength regime 80–82  - fiber laser, with SCPEM Q-switch 38, 39
  - fiber-optic collimators 294
  - fiber optics gyroscopes (FOGs) 301
  - field-induced electrostriction strain 275
  - field of view (FOV) 112, 114–116, 122, 123, 129, 131, 345–346, 457
  - film-loaded surface acoustic wave guide 132
  - finite element method (FEM) 29, 176–178, 181, 343, 346, 363

- flow injection analysis (FIA) 89, 109–112
- fluorescence loss in photobleaching (FLIP) technique 93
- fluorescence technique 93
- focused ion beam (FIB) 292, 323–325
- free-space optical (FSO) communication 301
- free-space optical isolator design 191
- free spectral range (FSR) 294, 325, 330, 336, 337
- freestanding microdisk 325
- Fresnel reflection 16, 17, 435
- Fresnel zone plates 461, 463, 464
- g**
- gallium 64, 152, 199, 359
  - germanium 64, 82, 359
  - Glan–Thompson prism 20, 21
  - gold electrodes 292, 313, 344, 449
  - gyrotropic permittivity 143–144
- h**
- half wave electric field 313, 321
  - half-wave plate 21–23, 347
  - half-wave voltage 275–277, 281, 290, 307, 308, 316
  - harmonic frequency 336
  - high-density MO recording 239–245
    - hybrid recording 244–245
    - near-field recording 244
    - recording density 242–244
    - resolution of optical readout 239–242
  - high-resolution camera (HRC) 112, 114
  - high-resolution color camera (HRC) 113
  - high-speed optical modulators 340
  - Holman’s device-level analysis 269, 338
  - holographic data storage 409, 419, 423–425
  - holographic displays 452–453
  - holographic interferometry techniques 444–451
    - advantages 445
    - phase-shifting 446
    - real-time holographic interferometry 446, 447
  - holographic optical coherence imaging 455–457
  - holographic polymer dispersed liquid crystal (H-PDLC) 423, 457–467
  - electrically switchable cylindrical Fresnel lens 460–467
  - wavelength switch 458–460
- Huth’s equation 221, 239
- hybrid recording technique 244–246
- hydrated/hydroxylated salts 114
- hydrofluoric (HF) 325
- i**
- index ellipsoid 1–3, 7, 30, 31, 271–273
  - indium phosphide 306, 359
  - indium tin oxide (ITO) 323, 330, 355, 356, 358, 359, 362–364, 367, 371, 440, 458, 462
  - infrared (IR) 64, 295, 327, 426
    - spectrometer 113
    - multispectral imaging 86–88, 90
    - reflectance spectroscopy 114, 121
  - Infrared Spectrometer for ExoMars (ISEM) 112–121
  - insertion loss (IL) 157, 181–183, 189, 201, 202, 294, 304, 306, 316, 330, 333–337, 366, 369, 458–460, 474
  - integrated combiner modules 473
  - integrated optical electric field sensor (IOES) 314–316, 319, 323
  - integrated optical phase modulator 277
  - integrated-optic directional couplers 283, 284
  - integrated optics 197, 266, 288, 295, 320–323, 340, 367
  - integrated optoelectronic devices 339
  - integrated plasmonic circuits 269, 355
  - intensity-modulation-type modulators 154
  - intensity modulators (type 1) 278–279
  - intensity modulators (type 2) 279–280

- inter-band photorefractive effect 417–418, 422, 434, 435, 439
- interference filters 18, 63, 94, 95
- iron-doped LiNbO<sub>3</sub> 425
- k**
- Kerr coefficient 268, 271, 328
- Kerr effect 148, 149, 151, 152, 194, 195, 225, 226, 234, 247, 265, 266, 270, 274, 327, 328, 348, 349
- Kerr electro-optic birefringence 265, 274
- Kerr electro-optic effect 148, 265, 274
- Kerr ellipticity 144–145
- Kerr medium 271
- Kerr rotation 144–145, 149, 159, 226, 227, 232, 233
- Klein–Cook parameter 62
- KNbO<sub>3</sub>, electro-optic properties of 269
- l**
- lanthanum (La) 293
- laser Doppler vibrometer (LDV) 75–76
- laser power modulation (LPM) process 222–224, 239
- laser ultrasound 454
- law of reflection 16
- lead lanthanum zirconate titanate (PLZT) 266, 268, 269, 293–295, 328, 338
- electro-optic tunable etalon 294
- lead magnesium niobate-lead titanate (PMN–PT) 266, 268–269, 328–338
- electro-optic Q-switching 330–332
- electro-optic tunable filter 329–330
- PC 334–335
- VOA 332–334
- lead molybdate (PbMoO<sub>4</sub>) crystal 125, 126
- light polarizing devices 20–24
- optical attenuators 22–23
- optical isolator 22
- phase plate 21–22
- polarization rotator 23–24
- polarizing plate 20
- polarizing prism 20–21
- LiNbO<sub>3</sub> crystals 41, 42, 51–53, 298, 303, 316, 321, 348, 428, 429, 439
- electro-optic field sensors 310–323
- nanophotonic modulator 306–310
- LiNbO<sub>3</sub> microresonator 323–327
- linear birefringence 153, 208, 209, 211
- linear electro-optic coefficient 271
- linear electro-optic constants 272
- linear electro-optic effect 265, 266, 270–274, 415, 429, 434, 445
- primary effect 273
- secondary effect 273
- linear magnetic birefringence (LMB) 147
- linear magnetic dichroism (LMD) 149
- linear polarization 10–11, 13, 15, 24
- equal amplitudes 10, 13
- unequal amplitudes 10–11, 13
- linear polarizer 13, 22, 161, 162
- liquid crystal twisted nematic
- polarization rotator cell 24
- lithium heptagermanate (Li<sub>2</sub>Ge<sub>7</sub>O<sub>15</sub>) crystals 53–55
- lithium niobate (LiNbO<sub>3</sub>) 51, 64, 131–134, 268, 295, 298–327, 412, 425, 433
- application 299–327
- balanced 90° coherent receiver 304–305
- quadrature modulator 303–304
- space environment 301–303
- modulators 300
- polarization beam splitter 132
- surface acoustic wave guide 132–133
- waveguide reflector 133–134
- lithium niobate (LN) crystal 348, 425
- of Q factors 323
- lithium tantalate (LiTaO<sub>3</sub>) 295–298
- EO lens 295–298
- EO scanner 295–298
- SHG 295–298
- local oscillator (LO) laser 304
- long persistence holograms 452

- low-loss waveguide 298, 310, 370  
 Lunar infrared spectrometer (LIS) 113
- m**
- Mach–Zehnder electro-optic modulators 268, 328  
 Mach–Zehnder interferometer (MZI) 278, 300, 319  
 Mach–Zehnder magneto-optic (MO) modulator 166  
 Mach–Zehnder modulators 169, 289, 313  
 Mach–Zehnder optical waveguide interferometer 289, 316  
 magnetic amplifying magneto optical system (MAMMOS) 241  
 magnetic field-measurement systems 205  
 magnetic field modulation (MFM) process 222, 224–225, 240  
 magnetic fluid (MF) 152–156, 218–219  
   birefringence effect 155  
   description 153  
   dielectric constant/refractive index of 155  
   properties 154  
 magnetic fluid based magneto-optic modulator 170–174  
 magnetic fluid-based modulator applications 154  
 magnetic fluid sensor 218–219  
 magnetic force sensors 207, 211–219  
   magnetic fluid sensor 218–219  
   magnetostrictive sensors 212–215  
   Terfenol-D sensors 215–218  
 magnetic memory chips (MRAMs) 160  
 magnetic super resolution (MSR) 234, 240, 242  
 magneto-optical (MO) circulators 177–190  
   multiple-port integrated optical circulators 186–189  
   tetrahertz 189–190  
   T-shaped 177–186  
 magneto-optical isolators 190–205  
   nonreciprocal phase-shift isolator 193–197  
   QPM Faraday rotation isolator 192–193  
   silicon-based MO isolator and circulator 197–201  
   THz isolators 201–205  
   TM-mode waveguide isolators 194–204  
 magneto-optical recording 219–247  
   high-density 239–245  
   laser power modulation process 222–224  
   magnetic field modulation 224–225  
   principles of 220–222  
   readout 225–226  
   ultrahigh-density 245–247  
 magneto-optical recording materials 227  
   characteristics 227  
   exchange coupled films 233–236  
   magnetic film properties 226  
   metallic multilayers 236–239  
   RE-TM amorphous alloy films 228–233  
 magneto-optical sensors 205–219  
   all-fiber sensors 207–209  
   bulk optic sensors 209–211  
   magnetic force sensors 211–219  
 magneto-optic effect 143, 145, 147–149, 157, 159, 161, 191, 197, 198  
   absorption mode 149  
   reflection mode 148–149  
   of RE-TM films 232  
   transmission mode 145–148  
 magneto-optic Kerr effect (MOKE) 143, 151–153, 159, 225, 226, 233, 238  
   in bilayer MnPSe<sub>3</sub> 159  
   high temperature noncollinear antiferromagnets 159  
 magneto-optic modulator 161–177  
   Mach–Zehnder magneto-optic modulator 166–169  
 magneto-optic spatial light modulator 161–166

- magneto-optic spatial light modulator (MOSLM) 161–166
- magneto-photonic crystal (MPC) circulators 178, 181
- magnetoresistive field sensors 206
- magnetostrictive sensors 212–215
- magnetron sputtering 216, 340
- main controller (MC) 118
- mast-mounted optical box (OB) 115
- metal–insulator–metal (MIM) 360, 362–364, 368, 370
- metal/magneto-optic plasmonic lens (MMOPL) 202–204
- metal/MO plasmonic waveguide (MMOPW) 201, 202
- metal organic chemical vapor deposition (MOCVD) 290, 339, 340
- metal–oxide–semiconductor (MOS) 358, 365
- Michelson *vs.* photorefractive crystal interferometer 449, 450
- MicrOmega 114, 115
- microresonators 268, 323–327
- Mn-doped III–V semiconductors, ferromagnetism in 152
- MO disk 219, 228
- mode locker 68, 81, 82
- modulation transfer function (MTF) model 66, 67, 71–72
- monochromatic optical isolator 22
- mono-shielding electrode 313, 314
- Morin transition 160
- Muller, H. 33, 35
- multicolour holographic stereograms 453
- multiple-port integrated optical circulators 186–189
- n**
- nanoelectromechanical systems (NEMS) 339
- nanoelectronics 371
- nanophotonic 293, 306–310, 355, 365, 370, 371
- nanophotonic LiNbO<sub>3</sub> modulator 306–310
- nano-second speed PLZT optical switch 294–295
- narrow-band continuous-wave tunable diode laser 325
- narrow band hyper spectral systems 101
- navigation cameras (NavCam) 113
- near-field recording technique 244
- near infra-red (NIR) spectrophotometer, AOTF-based 95–98
- negative uniaxial medium wave surface 5
- Nelder–Mead optimization method 182
- nematic liquid crystals 270
- Nicol prism 20, 21
- NIR spectropolarimeter, AOTF based 98–101
- nonlinear optical applications 266, 288, 340, 425
- nonlinear optical coefficients 269, 338
- nonreciprocal-loss isolator 191
- 1.5-μm nonreciprocal-loss waveguide optical isolator 152
- nonreciprocal phase-shift isolator 191–193
- non-resonant acousto-optic modulator 64
- non-return-to-zero (NRZ) 309
- o**
- onboard computer (OBC) controls 120
- on-chip electro-optic tunable LN microresonator 324
- optical attenuators 22–23
- optical beam scanner 344, 350–354
- optical box (OB) 115, 116, 118, 119
- optical circulator 80, 157, 177, 178, 186, 187, 198
- features 177
- magneto-optical 177–190
- three-port 178, 179
- optical filters 18, 19, 118, 327, 329, 432, 433, 438
- optical indicatrix 1–3, 31, 61
- optically induced waveguides 426

- optical isolator 22, 143, 151, 152, 157, 158, 190, 191, 193, 195, 198–200  
 optical parametric oscillation 269, 338  
 optical powers 63, 214, 219, 278, 282–284, 313, 322, 325, 332  
 optical recording media 219  
 optical switching device 266, 288, 290, 339  
 optical waveguides 266, 268, 269, 279, 288, 299, 307, 308, 319, 321, 328, 338–340, 343, 344, 425  
 optic axis 2, 3, 6, 7, 127, 222, 299  
 opto-ceramic harmonic elements 336  
 opto-ceramic (OC) materials 332, 335  
 opto-ceramic Q-switches 331  
 ordinary ray 5, 7, 84  
 ordinary wave surface 4
- p**
- Panoramic camera (PanCam) 112–115, 120, 121  
 Peltier-cooled InAs detector 112  
 perovskite–structure material 338  
 phase-modulation-type modulators 154  
 phase plate 21–22  
 phase-shifting 193, 446  
 phase-stepping technique 446  
 phenomenological theory, of  
     photoelasticity 30–33  
 photoelastic accelerometer 41–45  
 photoelastic devices 35–50  
 photoelastic force sensor 45–50  
 photoelasticity 1, 27–55, 61, 273  
     atomic theory 33–35  
     defined 27  
     history of 28–30  
     phenomenological theory 30–33  
     principle of 27–28  
 photoelastic modulator (PEM) 36–38, 51  
 photoelastic path difference 270  
 photoelastic Q-switch 38–41  
 photopolymers 423–425, 451, 457  
     coherence gated holographic imaging 455–457  
     holographic autocorrelator 453–454  
     holographic displays 452–454  
     laser ultrasonic receiver 454  
     surface waveguide 457  
     ultrasound-modulated optical tomography 454–455  
 photorefractive damage threshold 299  
 photorefractive effect 409–475  
     band diagram behaviour 410  
     change of refractive index 411  
     charge transport 410–411  
     conventional model of 412–413  
     disadvantage 440  
     in electro-optic crystals 422  
     features 419  
     generation of charge carriers 410  
     holographic data storage 419–420  
     inter-band 417–418  
     light induced waveguides 421–422  
     photorefractive index gratings 413–415  
     space charge field, for sinusoidal illumination 415–416  
     trapping of mobile carriers 411  
     two waves mixing/two beam coupling 420–421  
 photorefractive index gratings 413–415  
 photorefractive information storage materials (PRISM) 424  
 photorefractive sensitivity 269, 338  
 photorefractive switches 439–444  
 photorefractive tunable filters 432–439  
 photorefractive waveguides 425–432  
 photosensitive glass 423, 467–473  
 photosensitive materials, requirements for 468  
 piezo-optic coefficients (POCs) 51, 52, 54, 55  
 planar waveguide fabrication, in  $\text{Sn}_2\text{P}_2\text{S}_6$  crystals 426  
 planar waveguides 282, 295, 296, 426, 428  
 plane of incidence 5, 16, 19, 457

- plasmonics 201–204, 269, 354, 370  
 interferometer 266, 292–293  
 modulators 293, 358, 359, 363, 364,  
     366, 369, 371  
 plasmon-mediated transmission 293  
 PLZT ceramic element 266, 293  
 PLZT optical switch subsystem 294  
 Pockels coefficient 271, 277, 283  
 Pockels effect 144, 265, 270, 274, 277,  
     287, 326, 347–349, 415, 424, 439,  
     441, 442, 445  
 Pockels effect index modulation 270  
 Pockels electro-optic constants 272  
 Pockels medium 271  
 pockels readout optical modulator  
     (PROM) 287–288  
 Pockels theory 31  
 Poincare sphere 334, 335  
 polarisation-dependent loss (PDL)  
     333–335, 341  
 polarization controller (PC) 163, 164,  
     269, 316, 325, 334–336  
 polarization dependent loss (PDL)  
     333–335, 341  
 polarization maintaining optical fibers  
     (PMF) 154, 304, 321  
 polarization mode dispersion (PMD)  
     334  
 polarization of light 1, 8–16, 20, 36, 38,  
     161, 191  
     birefringent wave plate 14–16  
     circular polarization 11–12  
     elliptical polarization 12–13  
     linear polarization 10–11  
     polarizer and polarizing beam  
         splitters 13–14  
     reflected and transmitted  
         at an interface between two media  
             16–17  
         at multilayer thin film coatings  
             17–20  
     polarization rotator 23–24, 192  
     polarizers 13, 14, 19, 22, 24, 27, 116,  
         191, 279, 280, 285, 329, 341, 447,  
         464, 465  
     polarizing plate 20, 21  
     polarizing prism 20–21  
 Polaroid “H-Sheet” 14  
 positive uniaxial medium wave surface  
     5  
 potassium dihydrogen arsenate (KDA)  
     266  
 potassium dihydrogen phosphate (KDP)  
     266  
 potassium niobate ( $\text{KNbO}_3$ ) 269,  
     338–339, 412  
 potassium tantalate niobate  
     ( $\text{KTa}_{1-x}\text{Nb}_x\text{O}_3$ ) 348  
 potassium tantalate niobate (KTN)  
     266, 339–354  
     crystals 269  
     electro-optic phase modulator  
         340–346  
     EOD 347–351  
     fast varifocal lenses 346–347  
     optical beam scanner 350–354  
 potassium tanta optical beam scanner  
     353  
 power supply unit (PSU) 119  
 power-transfer ratio 282, 283  
 primary effect 273  
 primary optic axes 3, 4  
 proton exchange (PE) 132, 268, 295,  
     298  
 Pt/Co multilayers 238  
 pulsed laser deposition (PLD) 289,  
     339, 340  
 “push–pull” modulators 303
- q**
- Q-switched diode pumped solid-state  
     (DPSS) 331  
 Q-switches 63, 74, 268, 331, 332, 346  
 Q-switching 38, 51, 59, 78–83, 299,  
     330, 331  
     acousto-optic modulation 78–79  
     distributed feedback-fiber laser setup  
         82–83  
     FBG, acousto-optic interaction 79  
     mode-locking regime 80–82  
 quadratic electro-optic coefficient 274  
 quadratic electro-optic effect (QEO  
     effect) 265, 270, 274–275, 339,  
     348

- quadrature phase shift keying (QPSK) 303, 304
- quarter-wave plate 15, 21, 22
- quartz 6, 22, 36, 50, 64, 76, 86, 88, 99, 265, 270
- quartz retardation plates 24
- quasi-phase matching (QPM)
- Faraday rotation isolator 191–193
  - principle 299
- r**
- radio frequency (RF) wave 300
- radio-signal phase analysis 68
- Raman–Nath diffraction 59–62
- reactive LiNbO<sub>3</sub> etching 301
- real-time holographic interferometry (RTHI) 445–447
- reflective polarizer 14
- refractive index 7, 33–35, 40, 50, 51, 59, 61, 63, 73, 75, 99, 124, 154–156, 176, 177, 179, 193, 196, 205, 207, 209, 218, 265, 270, 271, 273, 275, 276, 280, 283, 288, 294, 300, 312, 313, 328, 333, 335, 341, 343, 346–349, 351–353, 358, 359, 409, 411, 415, 418, 419, 421, 422, 424, 426, 435, 437, 441, 457, 459, 461, 462, 464–466, 468, 470
- refractive index control 358
- retardation 21, 24, 28, 36, 38–40, 146, 156, 201, 277–280, 300, 334, 335, 341, 342
- s**
- satellite and space-based AOTF
- applications 112–124
  - SPICAM-IR spectrometer 121–124
- scanning speed, of AOTF 88
- secondary effect 273
- second harmonic generation (SHG) 266, 268, 269, 288, 295–297, 338, 339
- grating 295, 297
  - waveguides 269
- semiconductor optical isolators, ferromagnetic metals for 151, 152
- sensors, structure 314
- shunt resistance 119
- signal to noise ratio (SNR) 90, 226, 305, 335, 450
- silicates (hydr-) oxides 114
- silicon-based MO isolator and circulator 197–201
- silicon-ferrite photonic crystal, for THz circulator 190
- silicon waveguide-based modulators 364, 366
- single crystal LiTaO<sub>3</sub> photo-elastic modulator 51
- single crystal photoelastic modulator (SCPEM) 36–39
- sinusoidal filter 336, 337
- Smart-Spectra system 101, 102, 105, 106
- Sn<sub>2</sub>P<sub>2</sub>S<sub>6</sub> crystals, planar waveguide fabrication in 426
- sol–gel deposition 340
- solid immersion lens (SIL) 244, 245
- space-charge effect 349
- spatial light modulators (electrically addressed) 285
- spatial light modulators (optically addressed) 285–287
- spatial pattern of conductance 286, 287
- spectral resolution, of AOTF 88, 89
- SPICAM-IR spectrometer 121–124
- states of polarization (SoP) 10, 12, 212, 334, 335
- steady electric field 270, 277
- stress induced birefringence 28
- stress optical dispersion, of Li<sub>2</sub>Ge<sub>7</sub>O<sub>15</sub> crystals 53, 54
- strontium ruthenate (SrRuO<sub>3</sub>) 292
- structural phase transitions 358, 359
- submicrometer lithium niobate slab waveguides 268
- superconducting magneto-optic modulator 168
- superconducting single-flux-quantum (SFQ) logic systems 166
- surface plasmon polarisation (SPP) 292

- surface plasmon polaritons (SPP) 269, 355, 358, 364
- surface waveguide, in photopolymers 457
- switching voltage 284, 292, 466
- symmetric Mach–Zehnder interferometer 317
- t**
- tapered antenna array 316, 318
- TE1000 electro-optic tunable etalon 294
- tellurium dioxide ( $\text{TeO}_2$ ) crystals 86, 99, 116, 122, 125–131
- acousto-optical tunable filter 126–128
- acousto-optic deflectors 128–131
- acousto-optic lens microscope 128
- Terfenol-D sensors 215–218
- terahertz magneto-optical circulator 189–190
- terahertz magneto-optic modulator 174–177
- Thales Alenia Space-Italy (TAS-I) 119
- thermal lens spectrometer, AOTF-based 93–95
- thermoelectric cooler (TEC) 304
- thermomagnetic recording 220–222, 224, 225, 229, 230, 233, 244
- thermo-optic or nonlinear polymer 359
- thin film plate polarizer 20
- Thomas–Fermi screening theory 360, 361, 363
- three-component photoelastic waveguide accelerometer 41, 42
- three-dimensional waveguides (3D-WGs), in  $\text{LiNbO}_3$  428
- THz isolators 201–205
- based on metasurfaces 204–205
  - based on plasmonics 201–204
- Ti-deep diffused SAWG 132
- time delay 334
- time reversed ultrasonically encoded (TRUE) optical focusing technique 454
- Ti-sapphire laser 68, 296
- $\text{Ti}_3\text{AsSe}_3$  crystals 87
- TM-mode waveguide isolators 194, 195
- total internal reflection (TIR) 17, 211, 340, 457, 458
- transimpedance amplifier 119
- transmission type VBG 469–471
- transmitted light intensity 285
- transparent conducting oxide (TCO) 355–358, 360–371
- trapped charges 349, 411
- T-shaped magneto-optical circulators 177–186
- tunable Fabry-perot filter (TFPF) 329–331
- tunable Lyot filter (TLF) 329
- tuning coefficient 326, 327
- two-channel acousto-optic modulator 68, 69
- two waves mixing 419, 420
- u**
- ultra-compact plasmonic modulators 362–364, 366, 367
- ultrafast superconducting optoelectronics 166
- ultrahigh-density MO recording 246
- ultrasound-modulated optical tomography 454–455
- unbalanced Mach–Zehnder electric field sensor 321
- uniaxial crystals 2–6
- indicatrix for 3
  - ray surfaces of 4
  - wave surface 4
- unwrapping phase techniques 447
- v**
- vanadium dioxide 359
- variable gain tilt filters (VGTF) 335–338
- variable optical attenuators (VOA) 269, 332–334, 337, 338
- Voigt effect 147, 149
- voltage-induced birefringence 329

volume Bragg gratings (VBG) based devices and subsystems 473–475  
 volume Bragg gratings (VBG) filters 469–473  
   advantages 472  
   manufacturing 470  
   operation principles 469  
   recording 470  
   spectral response 472  
   in transmission/reflection mode 469  
   WDM combiners/splitters 473  
 volume holograms 433, 445  
 volume holographic data storage (VHDS) 423–425

***w***

waveguide electro-optic modulator 289–292  
 waveguide optical isolators 157, 191, 193, 199, 200  
 waveguide reflector 133–134  
 wavelength dependent loss (WDL) 333

wavelength division multiplexing (WDM) 83, 96, 154, 300, 329, 335, 346, 423, 458, 468, 471, 473

wavelength selectivity, of dynamic grating filter 437

wave surface 4–6  
   for biaxial crystals 5–6  
   ordinary and extraordinary 4  
   for uniaxial crystals 4–5

whispering gallery mode (WGM) 325, 326

Wide-angle camera pair (WACs) 113, 114

***x***

X-cut LiNbO<sub>3</sub> chip 303, 304

***y***

yttrium iron garnet (YIG) 156, 158, 167, 174, 191

***z***

z-cut lithium niobate (LiNbO<sub>3</sub>) 268  
 0-gap directional coupler waveguide 133

